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P Rractitioner's Docket No. <u>U 015850-2</u>

NOV 1 6 2006

# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In papelication of: Vladimir PAVLOVICH POPOV, et al

Application No.: 10/542,123 Group No.: 2823

Filed: December 9, 2005 Examiner: Q. Jefferson

For: METHOD FOR PRODUCING A SILICON-ON-INSULATOR STRUCTURE

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

# TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT BEFORE MAILING DATE OF EITHER A FINAL ACTION OR NOTICE OF ALLOWANCE (37 C.F.R. 1.97(c))

NOTE: 37 C.F.R. 1.97: "(c) An information disclosure statement shall be considered by the Office if filed after the period specified in paragraph (b) of this section, provided that the information disclosure statement is filed before the mailing date of any of a final action under § 1.113, a notice of allowance under § 1.311, or an action that otherwise closes prosecution in the application, and it is accompanied by one of:

- (1) The statement specified in paragraph (e) of this section; or
- (2) The fee set forth in  $\S 1.17(p)$ ."

NOTE: "If a final action or notice of allowance is mailed in an application and later withdrawn, the application will be considered as not having had a final action or notice of allowance mailed for purposes of considering an information disclosure statement." Notice of April 20, 1992 (1138 O.G. 37-41, 39).

#### CERTIFICATION UNDER 37 C.F.R. 1.8(a) and 1.10\*

(When using Express Mail, the Express Mail label number is mandatory; Express Mail certification is optional.)

I hereby certify that, on the date shown below, this correspondence is being:

#### **MAILING**

deposited with the United States Postal Service in an envelope addressed to the Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450.

37 C.F.R. 1.8(a)

37 C.F.R. 1.10\* (Preferred)

# TRANSMISSION

transmitted by facsimile to the Patent and Trademark Office. to (571)-273-8300

Date: November 14, 2006 Signature

WILLIAM R. EVANS

(type or print name of person certifying)

\* Only the date of filing (§ 1.6) will be the date used in a patent term adjustment calculation, although the date on any certificate of mailing or transmission under § 1.8 continues to be taken into account in determining timeliness. See § 1.703(f). Consider "Express Mail Post Office to Addressee" (§ 1.10) or facsimile transmission (§ 1.6(d) for the reply to be accorded the earliest possible filing date for patent term adjustment calculations.

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NOTE: 37 C.F.R. § 1.704(d): "A paper containing only an information disclosure statement in compliance with §§ 1.97 and 1.98 will not be considered a failure to engage in reasonable efforts to conclude prosecution (processing or examination) of the application under paragraphs (c)(6), (c)(8), (c)(9), or (c)(10) of this section if it is accompanied by a statement that each item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart application and that this communication was not received by any individual designated in § 1.56(c) more than thirty days prior to the filing of the information disclosure statement. This thirty-day period is not extendable."

NOTE: "If information submitted during the period set forth in 37 C.F.R. 1.97(c) with a certification is used in a new ground of rejection on unamended claims, the next Office action will not be made final since in this situation it is clear that applicant has submitted the information to the office promptly after it has become known and the information is being submitted prior to a final determination on patentability by the Office. However, the information submitted with a certification can be used in a new ground of rejection and the next Office action made final, [i]f the new ground of rejection was necessitated by amendment of the application by applicant. Where the information is submitted during this period with a fee, the examiner may use the information submitted, e.g., printed publication or evidence of public use, and make the next Office action final whether or not the claims have been amended, provided that no other new ground of rejection which was not necessitated by amendment to the claims is introduced by the examiner. See MPEP 706.07(a). If a new ground of rejection is introduced that is neither necessitated by an amendment to the claims nor based on the information submitted with the fee set forth in 37 C.F.R. 1.17(p), the Office action shall not be made final. Notice of April 20, 1992 (1138 O.G. 37-41, 39).

**WARNING:** 

"A petition for suspension of action to allow applicant time to submit an information disclosure statement will be denied as failing to present good and sufficient reasons, since 37 C.F.R. 1.97 provides adequate recourse for the timely submission of prior art for consideration by the examiner." Notice of July 6, 1992 (1141 O.G. 63). But see § 103(b) and (c), limited suspension of action in a continued prosecution application (CPA) filed under § 1.53(d) and in a request for continued examination (RCE) under § 1.114.

**WARNING:** 

No extension of time can be had under 37 C.F.R. 1.136(a) or (b) for filing an IDS. 37 C.F.R. 1.97(f).

# TIME OF TRANSMITTAL OF ACCOMPANYING INFORMATION DISCLOSURE STATEMENT

- 1. The information disclosure statement transmitted herewith is being filed *after* three months of the filing date of this national application or the date of entry of the national stage as set forth in § 1.491 in an international application or after the mailing date of the first Office action on the merits, whichever event occurred last but *before* the mailing date of either:
  - (1) a final action under § 1.113 or
  - (2) a notice of allowance under § 1.311,

whichever occurs first.

#### STATEMENT OR FEE

2.	Accompar	companying this transmittal is  (check either A or B below)					
A.	[]	a statement as specified in 37 C.F.R. 1.97(e).					
		OR					
В.	[X]	the fee set forth in 37 C.F.R. 1.17(p) for submission of an information disclosure					

#### METHOD OF PAYMENT OF FEE

3.	[ ]	Attached is a check in the amount of \$180.00
	. ,	

statement under § 1.97(c). (\$180.00).

[ ]	Charge Account No in the amount of \$  A duplicate of this request is attached.
If any additiona	al or lesser fees are due, please charge or refund deposit Account 12-0425.
Reg. No. 25,85	SIGNATURE OF PRACTITIONER  8
1105. 110. 23,03	WILLIAM R. EVANS
Tel. No.: (212)	(type or print name of practitioner) 708-1930
Customer No.:	P.O. Address
	/ I 1 0 D IID
	c/o Ladas & Parry LLP 26 West 61st Street
	New York, N.Y. 10023

**PATENT** 

### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

in re application of: Vladimir PAVLOVICH POPOV, et al

Serial No.: 10/542,123

Filed: December 9, 2005 Examiner: Q. Jefferson

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Attorney Docket No.: U 015850-2

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

NOV 16 2006

# INFORMATION DISCLOSURE STATEMENT

We draw the attention of the Examiner to the attached references which are also listed on the attached Form PTO-1449.

Respectfully submitted

Group No. 2823

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# CERTIFICATION UNDER 37 C.F.R. 1.8(a) and 1.10\*

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I hereby certify that, on the date shown below, this correspondence is being:

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		Signate	ure	$\rightarrow$
Date:	November 14, 2006	W	ILLIAM R. EVANS	
		(type of	r print name of person certify	ing)

\*WARNING:

Each paper or fee filed by "Express Mail" must have the number of the "Express Mail" mailing label placed thereon prior to mailing. 37 C.F.R. 1.10(b).

"Since the filing of correspondence under § 1.10 without the Express Mail mailing label thereon is an oversight that can be avoided by the exercise of reasonable care, requests for waiver of this requirement will not be granted on petition." Notice of Oct. 24, 1996, 60 Fed. Reg. 56,439, at 56,442.

FORM PTO-1449

## U. S DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO. SERIAL NO. U 015850-2 10/542,123

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

APPLICANT Vladimir Pavlovich POPOV et al. FILING DATE **GROUP** 

v 16 2006	(Use several sh	eets if necessary)		FI	LING DATE		GROUP		
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EVAMINED		U.S. P	ATENT DO	CUMENT	rs				
EXAMINER INITIALS	REFERENCE DESIGNATION	DOCUMENT NUMBER	DAT	E	NAME		FILING DATE IF APPROPRIATE		
	AA								
	AB								
	AC								
FOREIGN PATENT DOCUMENTS									
		D0CUMENT NUMBER	DAT	T)	COUNTRY		TRANSLATION YES NO		
•	AD						*****		
•	AE								
•	AF								
	OTHER ART (Including Author, Title, Date, Pertinent Dates, Etc.)								
	AG	Rieutord, F. et al. "Dynamics of a Bonding Front" Physical Review Letters (2005) PRL Vol. 94							
	АН	Takahagi, T. et al. "A Jpn. J. Appl. Phys. (2		Exposed to	Atmosphere"				
	AI	Gosele, U. et al. "Self-Progpagating Room-Temperature Silicon Wafer Bonding in Ultrahigh Vacuum" Appl. Phys. Lett. (1995) Vol. 67, No. 24, pp 3614-3616							
	AJ	Farrens, S.N. et al. "Chemical Free Room Temperature Wafer to Wafer Direct Bonding"  J. Electrochem. Soc. (1995) Vol. 142, No. 11, pp 3949-3955							
	AK	Tong, Q. Y. et al. "Low Vacuum Wafer Bonding" Electrochemical and Solid-State Letters (1998) Vol. 1, No. 1, pp 52-53							
	AL	Tong, Q. Y. et al. "Semiconductor Wafer Bonding: Science and Technology"  John Wiley & Sons, Inc. (1999) pp 52-53, and pp 122-127							
		emperature Si-Si Hydrophilic Wafer Bonding" ty (2003) Vol. 150, No. 3, G228-G231							
	AN	Dragoi, V. et al. "Plasma Activated Wafer Bonding for MEMS"  SPIE Proceeding 5836 (2005) paper no. 5836-19							
"Long-Term Stability of Vacuum-Encapsulated MEMS Devices AO VABOND-Deliverable 6.4 - Technology Guidelines on Vacuum								nding"	
Zhang, X. et al. "Low-Temperature Wafer Bonding Optimal O <sub>2</sub> Plasma Surface Time" Electrochemical and Solid-State Letters (2004) Vol. 7, No. 8, G172-G1							ent		
EXAMINER				DATE	CONSIDERED			-	
EXAMINER:		considered, whether or r						ation i	